**PATENT** 

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s):

Martin Hausner

Serial No.:

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Title:

METHOD FOR SELECTIVELY REMOVING MATERIAL FROM THE

SURFACE OF A SUBSTRATE, MASKING MATERIAL FOR A

WAFER, AND WAFER WITH MASKING MATERIAL

Our Ref. No.:

**BEET-09** 

Cincinnati, OH

February 11, 2005

Mail Stop PCT Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

## PRELIMINARY AMENDMENT

Sir:

Prior to examination of the above-identified application, please amend the application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 10 of this paper.